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Cryogenic Trapped-Ion System for Multiqubit Quantum Memory

(申请清华大学工学硕士学位论文)

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摘 要

论文的摘要是对论文研究内容和成果的高度概括²¹。摘要应对论文所研究的问题及其研究目的进行描述，对研究方法和过程进行简单介绍，对研究成果和所得结论进行概括。摘要应具有独立性和自明性，其内容应包含与论文全文同等量的主要信息。使读者即使不阅读全文，通过摘要就能了解论文的总体内容和主要成果。

论文摘要的书写应力求精确、简明。切忌写成对论文书写内容进行提要的形式，尤其要避免“第1章……；第2章……；……”这种或类似的陈述方式。

关键词是为了文献标引工作、用以表示全文主要内容信息的单词或术语。关键词不超过5个，每个关键词中间用分号分隔。

关键词：关键词 1；关键词 2；关键词 3；关键词 4；关键词 5

ABSTRACT

An abstract of a dissertation is a summary and extraction of research work and contributions. Included in an abstract should be description of research topic and research objective, brief introduction to methodology and research process, and summary of conclusion and contributions of the research. An abstract should be characterized by independence and clarity and carry identical information with the dissertation. It should be such that the general idea and major contributions of the dissertation are conveyed without reading the dissertation.

An abstract should be concise and to the point. It is a misunderstanding to make an abstract an outline of the dissertation and words “the first chapter”, “the second chapter” and the like should be avoided in the abstract.

Keywords are terms used in a dissertation for indexing, reflecting core information of the dissertation. An abstract may contain a maximum of 5 keywords, with semi-colons used in between to separate one another.

Keywords: keyword 1; keyword 2; keyword 3; keyword 4; keyword 5

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LIST OF SYMBOLS AND ACRONYMS

PI	聚酰亚胺
MPI	聚酰亚胺模型化合物, N-苯基邻苯酰亚胺
PBI	聚苯并咪唑
MPBI	聚苯并咪唑模型化合物, N-苯基苯并咪唑
PY	聚吡咯
PMDA-BDA	均苯四酸二酐与联苯四胺合成的聚吡咯薄膜
MPY	聚吡咯模型化合物
As-PPT	聚苯基不对称三嗪
MAsPPT	聚苯基不对称三嗪单模型化合物, 3,5,6-三苯基-1,2,4-三嗪
DMA sPPT	聚苯基不对称三嗪双模型化合物 (水解实验模型化合物)
S-PPT	聚苯基对称三嗪
MSPPT	聚苯基对称三嗪模型化合物, 2,4,6-三苯基-1,3,5-三嗪
PPQ	聚苯基喹噁啉
MPPQ	聚苯基喹噁啉模型化合物, 3,4-二苯基苯并二嗪
HMPI	聚酰亚胺模型化合物的质子化产物
HMPY	聚吡咯模型化合物的质子化产物
HMPBI	聚苯并咪唑模型化合物的质子化产物
HMA sPPT	聚苯基不对称三嗪模型化合物的质子化产物
HMS PPT	聚苯基对称三嗪模型化合物的质子化产物
HMP PQ	聚苯基喹噁啉模型化合物的质子化产物
PDT	热分解温度
HPLC	高效液相色谱 (High Performance Liquid Chromatography)
HPCE	高效毛细管电泳色谱 (High Performance Capillary electrophoresis)
LC-MS	液相色谱-质谱联用 (Liquid chromatography-Mass Spectrum)
TIC	总离子浓度 (Total Ion Content)
<i>ab initio</i>	基于第一原理的量子化学计算方法, 常称从头算法
DFT	密度泛函理论 (Density Functional Theory)
E_a	化学反应的活化能 (Activation Energy)
ZPE	零点振动能 (Zero Vibration Energy)
PES	势能面 (Potential Energy Surface)
TS	过渡态 (Transition State)
TST	过渡态理论 (Transition State Theory)

LIST OF SYMBOLS AND ACRONYMS

ΔG^\ddagger	活化自由能 (Activation Free Energy)
κ	传输系数 (Transmission Coefficient)
IRC	内禀反应坐标 (Intrinsic Reaction Coordinates)
ν_i	虚频 (Imaginary Frequency)
ONIOM	分层算法 (Our own N-layered Integrated molecular Orbital and molecular Mechanics)
SCF	自洽场 (Self-Consistent Field)
SCRf	自洽反应场 (Self-Consistent Reaction Field)

CHAPTER 1 INTRODUCTION

研究生学位论文撰写，除表达形式上需要符合一定的格式要求外，内容方面上也要遵循一些共性原则。

通常研究生学位论文只能有一个主题（不能是几块工作拼凑在一起），该主题应针对某学科领域中的一个具体问题展开深入、系统的研究，并得出有价值的研究结论。学位论文的研究主题切忌过大，例如，“中国国有企业改制问题研究”这样的研究主题过大，因为“国企改革”涉及的问题范围太广，很难在一本研究生学位论文中完全研究透彻。

1.1 论文的语言及表述

除国际研究生外，学位论文一律须用汉语书写。学位论文应当用规范汉字进行撰写，除古汉语研究中涉及的古文字和参考文献中引用的外文文献之外，均采用简体汉字撰写。

国际研究生一般应以中文或英文书写学位论文，格式要求同上。论文须用中文封面。

研究生学位论文是学术作品，因此其表述要严谨简明，重点突出，专业常识应简写或不写，做到立论正确、数据可靠、说明透彻、推理严谨、文字凝练、层次分明，避免使用文学性质的或带感情色彩的非学术性语言。

论文中如出现一个非通用性的新名词、新术语或新概念，需随即解释清楚。

CHAPTER 2 ION TRAPPING

2.1 插图

CHAPTER 3 EXPERIMENTAL SETUP

3.1 Introduction

3.2 The Cryostat

The cryostat is the key equipment of the cryogenic trapped ion system. We need to pay attention to some key technical indicators when choosing the model of the cryostat, designing the internal support structure and the assembly structure of the trap-related components. The most critical technical indicators are cooling capacity and vibration. Low temperature is the advantage of the cryogenic trap over the room-temperature trap. We can achieve low pressure by cryo-pumping to reduce the collision rate of trapped ions with residual background gas, thereby increasing the lifetime of trapped ions. The price of cryo-pumping is additional vibration, however, the vibration can be reduced to a degree that does not affect Quantum Gate Fidelity. In experiments, we often use these two parameters to characterize the cooling capacity. One is the lowest temperature that the system can reach when the cryogenic trap is not temperature stabilized, and the other is the heating power at the sample stage when the temperature of the cryogenic trap is stabilized above the liquid helium temperature zone and the vibration caused by liquid helium is reduced to a certain range. Another key technical indicator of the cryostat is the long-term stability at the sample, including changes in displacement and background electric field. This will affect the calibration period of the ion trap experiment. Calibration that is too frequent indicates a lack of robustness in the experiment system. There are several different types of cryostats on the market. One of these is the flow cryostat, which has lower cryocooler vibration noise but requires constant replenishment of cold liquid coolant, which is expensive and time-consuming. In contrast, the cryogenic trapped ion system in our lab uses a closed-loop Gifford-McMahon cryostat. This type of cryostat uses closed-cycle helium gas as operation material in cooling cycle and does not require constant refilling of the coolant. It is very convenient to use and cheap to maintain as it only needs external electric supply. One of the advantages of this closed-loop cryostat is that it has a Vibration Isolation System (VIS). The vibrating cold finger is mechanically separated from the main vacuum by a helium-filled exchange gas region at a pressure 0.03 bar above atmospheric. The VIS is the only mechanical coupling between the cold head and the main vacuum apparatus which is mounted on an optical breadboard. In the VIS

region, it is sealed with a helium-confined rubber bellows. The helium gas serves as the thermal link between the cold finger and the sample stage where the ion trap is mounted. Another advantage of this closed-cycle cryostat is that its structure is relatively simple, and we can increase cooling capacity and reduce vibration through optimized design, because it is difficult to optimize each parameter independently in a complex system. The cryostat is model SHI-4XG-15-UHV, designed and manufactured by Janis Inc. In order to reduce vibration, we provide some design suggestions. The cryostat consists of a cold head, an exchange gas chamber and a vacuum chamber. The cold head is powered by a helium compressor. The models of cold head and helium compressor are RDK-415D2 and F70-H produced by Sumitomo Corporation of Japan. The cold head features two stages with different cooling powers: the 40 K stage has XX W, and the 4 K stage has XX W. The cold head must be fixed near the vacuum chamber, but there are only three interfaces of the cold head: the power supply, the supply high-pressure helium tube and the return high-pressure helium tube. Therefore, we placed the helium compressor and water cooler in the grey room of the laboratory to further isolate the source of vibration noise. The single continuous running time of the cold head can exceed 10,000 hours, which is enough for us to carry out long-term experiments. The exchange gas chamber is mainly composed of rubber bellow, helium pressure gauge and some helium valves, the top and bottom are respectively connected to the cold head and the vacuum chamber. The role of bellow is to reduce the vibration generated by the cold head and directly transmitted to the vacuum chamber, because rubber is more elastic than stainless steel. I think it is worth trying to replace the rubber bellow with a stainless-steel sheet that has been bent many times, because using a rubber bellow may cause leakage in the long-term operation of the system. Leakage of rubber bellow may come from three aspects. Firstly, the rubber material will deteriorate after a long-time use, our system has a leakage problem after about 2 years of operation, which is manifested as water inside the exchange gas chamber after the process of cooling down and warming up. Secondly, the rubber bellow is prone to defects during machining, we contacted our supplier to process a new rubber bellow after we found the leakage problem, and found that some of the rubber bellow had defects on the surface during many attempts. Finally, the sealing method of rubber bellow is worse than that of stainless steel, our cryostat uses o-ring to seal rubber bellow. We tried to have the supplier process different rubber bellow to test the leakage, such as testing different materials and thickness of rubber bellow, in some poor cases after a single cooling

and reheating process will appear leakage, we finally used silicone rubber bellow and the thickness is twice the original and no leakage has been found so far.

3.3 Low Temperature and UHV System

The vacuum chamber resembles a cylinder with a diameter of about XX and a height of about XX. Externally, the upper part of the vacuum chamber has some feedthroughs connecting the electrical equipment to the vacuum equipment, and the lower part is a spherical octagon. The top of the vacuum chamber is in contact with the exchange gas chamber, and the bottom is the re-entrant window. In our experiments, we used a total of three electrical feedthroughs, one DC feedthrough to drive the voltage signal to the electrodes of the trap, another DC feedthrough to drive the thermometer and heater in the vacuum chamber, and an RF feedthrough to drive the RF signal to the resonator. Below them, there are a total of three Vacuum feedthroughs, one connected to an ion gauge (Agilent UHV-24P) to monitor the vacuum level in the vacuum chamber, one connected to a NEG-Ion pump (SAES NextTorr Z100) to pump out hydrogen, since hydrogen is the least efficiently cryo-pumped gas, and an angle valve to pump out vacuum during system maintenance. A spherical octagon holds eight XX diameter windows to provide optical access in the horizontal plane, the windows are made of UVFS and have different wavelength optical coatings according to the optical path design. We replaced one of the windows along the trap axis with an oven feedthrough, and installed both enriched ^{171}Yb oven and enriched ^{174}Yb oven on it, and finally tested them to work. However, assembly errors during installation may cause the Yb flux cannot enter the trap during ion loading, we can increase the translation degrees of freedom when designing the part to solve this problem. According to our experience, because of the large divergence angle of Yb flux, we just need to be able to see the trap and oven through the opposite window. The re-entrant window located at the bottom of the vacuum chamber has a diameter of XX, below which is the imaging system. The maximum numerical aperture allowed for imaging ions along the vertical direction is XX. The Re-entrant window is surrounded by a cake-shaped aluminum base placed on an optical breadboard, and the base carries the full weight of the vacuum chamber. We tried to fasten between the upper part of the vacuum chamber and the optical breadboard with an aluminum sloped beam, but it did not reduce the vibration of the trap, indicating that the current support structure is solid enough. The main components inside the vacuum chamber are the 40K shield, the 4K

shield and the sample stage. These two shields are used to shield the ion trap from room temperature blackbody radiation, their material is aluminum, but copper may be a better choice because copper material has a higher thermal conductivity. The bottom of the two shields are eight 1" UVFS windows, which correspond to the spherical octagon and have the same optical coating. The glass is fixed in the groove by the Teflon holder in order to keep the windows from being crushed during the cooling procedure, however, because of the elasticity of Teflon, the positioning accuracy of the windows is poor, which may be the main source of optical aberration. The top of the 40K shield is in contact with the 40K stage of the cold head through the helium gas in the exchange gas chamber, which is usually higher than 40K, we named it that way just because it is intuitive. The top of the 4K shield is fixed to the sample stage, which is made of oxygen-free copper with a gold-plated surface to obtain a high thermal conductivity and to prevent oxidation during system maintenance. The sample stage and the 4K stage of the cold head are separated by a heat exchanger and cryogenic helium gas. The 4K stage can reach temperatures below 4K, and the heat exchanger is composed of a series of concentric circular oxygen-free copper sheets, which are designed to increase the cooling capacity at the sample stage. However, if the position between a pair of heat exchangers is shifted during operation and touches each other, it can introduce large vibrations to the sample stage, for example when floating the optical table. Although the cooling power of the 4K stage in the cold head reaches XX W, the cooling capacity of the sample stage in the vacuum chamber, which is directly available to the user, is much lower. The reduction of the cooling capacity comes from the heat conduction between the 4K stage and the sample stage and the heat leakage from the environment. In order to improve the heat transfer between the 4K stage and the sample stage, we can increase the surface area of the heat exchanger, we can also fill the exchange gas chamber with sufficient helium gas, and it is necessary to use oxygen-free copper to produce thermally conductive parts. In our experiments, we use auto gas charging system to stabilize the helium pressure in the exchange gas chamber at a fixed positive pressure. It is worth noting that the rubber bellow loses its vibration isolation function under negative pressure, and the life of the rubber bellow is reduced. The auto gas charging system was designed by PHYSIK and is based on the principle of using a PLC to read the helium pressure gauge and control the opening and closing moments of the helium valves, which will eventually stabilize the helium pressure gauge at 1.03 bar. There are two helium valves to control the helium inlet and outlet, and

one safety valve to allow excess helium to escape, preventing the bellow from bursting when the auto gas charging system is not working. The temperature stabilize system is a kit we purchased from Janis Inc. and consists of a thermometer, heater and temperature controller. The thermometer (DT-670-CU-HT-1.4H) is located inside the sample stage in the vacuum chamber and has a measurement range of 1.4K-500K, covering the cryostat operating range of approximately 4K-300K. The heater is a 25 Ohm resistor very close to the thermometer. The DC lines of the heater and the thermometer are connected to the temperature controller (Model 26 from CryoCon) on the instrument rack via a DC feedthrough on the vacuum chamber. In low temperature operation, the temperature of the Sample Stage can be stabilized at $6\text{K} \pm \text{XXmK}$ for a long time by setting the appropriate PID parameters. The output power of the heater is about 350mW, which means that the cooling power of the sample stage has a margin of 350mW. The auto gas charging system and The temperature stabilize system are the key systems for the long-term stability of the cryostat. Although the temperature of This cryostat has almost no drift, we can observe that the trap can shift $\pm 1 \mu\text{m}$ during the experiment. The operation to avoid the effects of such position shifts by frequent calibration of the system parameters is very complicated, so this instability can be fatal for an experimental system. The long drift of the sample stage comes from the mechanical structure of the cryostat. The auto gas charging system can only stabilize the helium pressure near the rubber bellow, and the 40K stage and 4K stage of the cold head are not stabilized. Therefore, the pressure and temperature in the contact part of the vacuum chamber and the exchange gas chamber cannot be stabilized for a long time. However, this part is the support point of the sample stage, so the sample stage will be disturbed by these external environmental changes. We can consider fixing the sample stage to the room temperature area of the vacuum chamber, which will not move if the laboratory environment is stable, but this will inevitably increase the heat leakage from the room temperature area. In our experiments, we first pumped the vacuum chamber to 1E-6 mBar at room temperature using the Turbo Pump, then activated the NEG-Ion Pump for about 2 hours, and at the end of the operation the vacuum chamber vacuum level dropped to 1E-8 mBar. The vacuum chamber can reach a vacuum level of 3E-10 mBar with the effect of the cryo-pump.

3.4 Helical Resonator and Segmented Blade Trap

The blade trap forms a capacitor of approximately XX pF. In order to drive this capacitor, i.e. to apply a high voltage signal to it, we need a larger helical resonator to form the LC oscillation circuit and to achieve impedance matching. The two components are therefore closely linked. The helical resonator and the blade trap are both located inside the 4K shield of the vacuum chamber. The helical resonator is fixed underneath the sample stage and then the blade trap is fixed underneath the helical resonator. This ensures that the helical resonator and the blade trap are very close to each other and that their temperatures are equally stable. At the same time the low temperature allows the resistance in the oscillator circuit to be significantly reduced, which helps to increase the Q factor of the oscillator circuit. The helical resonator and the blade trap are used as a single unit and its input and output are achieved via RF and DC electric feedthrough.

3.4.1 Design of Helical Resonator

The circuit models for the helical resonator and the blade trap have been well studied. In practice, we have developed a very mature design procedure with a high quality factor, choosing only two parameters $\frac{r}{R}$ and $\frac{L}{C}$ to optimise the performance of the helical resonator with the quality factor as the objective function. We can calculate the loading frequency in the empirical parameter regime using the trap capacitance and the quality factor. Typically, $\frac{r}{R} \approx 1.5$ and $\frac{L}{C} \approx 0.5$ is a good choice, and if the loading frequency meets our requirements we will try to choose the highest quality factor around this parameter range. A two-wire spiral resonator is much more complex than a single-wire spiral resonator because of the coupling between the two coils. However, for the sake of simplicity we are still using the model and we can achieve an accuracy of about $\pm 5\text{MHz}$. To ensure that the phase and amplitude of the two coils are the same, we use a parallel capacitor, which is shorted when connected to the RF feedthrough, with a capacitance of approximately 300 nF. The two-wire design is designed to help minimise micro-movements by applying a DC voltage to the RF electrodes, so we need to ensure that the RF signal on the coil is grounded and the DC voltage is not, this is achieved by a 300 nF capacitor connected to the shield. In addition, we added an RC filter before the DC voltage was connected to the coil.

3.4.2 Assembly of Helical Resonator

The material used for the body of the helical resonator is oxygen-free copper, which is characterised by its very low resistivity and high thermal conductivity. The low resistivity helps to obtain a high Q factor, but the oxygen-free copper is susceptible to oxidation during processing, so the oxide film needs to be removed before assembly. After the helical resonator has been assembled, it needs to be placed in a vacuum enclosure to prevent oxidation.

The main parts of the helical resonator were machined according to the design parameters: the antenna cover, the top cover, the middle part, the bottom cover and the helical coils, which were then cleaned in the ultrasound machine using acetone and ethanol. After drying these parts with nitrogen and soaking them in organic acid for 5 minutes, it can be observed that the surface oxide film disappears and turns purplish red. We soak the parts in plenty of distilled water to remove the residual organic acid and then dry the parts with nitrogen. The cleaning of the parts of the main part of the copper tube is now complete. This part needs to be done carefully, as the oxide film on the helical resonator surface affects the Q factor.

We also need to prepare and clean the rest of the parts according to the design parameters to meet the ultra-high vacuum requirements. We then soldered the circuit components together using lead-free solder. The parts are then assembled with stainless steel screws, each requiring a resilient pad to prevent the screws from loosening at low temperatures.

3.4.3 Assembly of Blade Trap

The advantage of the blade trap is that it is easy to process and assemble, but the disadvantage is that the assembly error is higher compared to the surface trap or the monolithic trap, which causes an asymmetry in the electrostatic potential at the centre of the trap where the ions are located, i.e. a deviation from the linear trap configuration. When designing the blade trap for use in the cryostat, we need to take care that the material has a high thermal conductivity and that the connections between the components are sufficiently tight. In this way we can achieve the lowest temperatures on the blade trap. This helps to obtain a higher vacuum level and to extend the life of the ions.

The blade trap consists of four blade-shaped electrodes, one pair of DC electrodes and one pair of RF electrodes. The blade is processed by laser cutting the ceramic substrate and then plating the surface with a gold layer. The electrodes are machined with a certain

amount of error and defects on the surface of the electrode closest to the ion produce a high level of electrical noise, which can be reduced by improving the process. We have machined a sapphire adapter plate and mounted the blade on the sapphire adapter plate and then mounted the sapphire adapter plate on an oxygen-free copper holder. We designed this adapter to avoid a short circuit between the blade and the ground (the blade holder). In order to increase the thermal conductivity, we need to cover these contact surfaces with indium foil. For the fixing of the components we used stainless steel screws and used resilient pads on each screw. This is to prevent the screws from loosening during the cooling down process, and to prevent the blade from being crushed by excessive torque when tightening the screws. Once installed we had to fine-tune the position of the sapphire adapter under the microscope to keep the assembly error small enough. This operation makes use of the fact that the diameter of the through-hole is slightly larger than the diameter of the screw. Since the assembly is done by hand, this part of the assembly error is unavoidable.

The connection of the blade electrodes is mainly done by means of gold ribbon (AME-TEK) and Kapton insulated wire (Accu-Glass Products). When selecting materials we need to be aware of ultra-high vacuum and cryogenic compatibility. Some of the circuit connections are made prior to assembly and the rest is done afterwards. Before assembling the blade, a 820pF capacitor is fixed with silver epoxy between each DC electrode and ground on the two DC blades. The purpose of this capacitor is to create a low impedance between the DC electrodes and ground, reducing the voltage splitting of the RF signal on the DC electrodes. The gold ribbon is connected to the electrodes with the spot welder at one end and to the pads of the PCB with solder at the other. We will later connect the pads to the corresponding connections with Kapton insulated wire, where the DC electrode wires are connected to the corresponding wires from the DC feedthrough through the heat sink twice, and the two RF electrode wires are connected to the two wires at the output of the helical resonator.

3.5 Yb Oven

In order to generate the atomic beams of Yb, we built two separate ovens from two stainless steel tubes, but integrated into a single feedthrough and both able to be used to load ions. The ^{171}Yb oven has an abundance of 90% and The ^{174}Yb oven has an abundance of 98%. As the Yb source is in block form, we need to cut it into small pieces

and insert it into the stainless steel tube.

In order to achieve UHV compatibility we chose to use copper, stainless steel and Macor when machining the parts of the oven. Before assembly and testing, we cleaned all the parts inside the ultrasound machine using acetone and ethanol as solvents. All the parts were assembled according to the drawings and the copper wires on the feedthrough were attached to the stainless steel base, which was all screwed in place. We then used a spot welder and welded the stainless steel tube to the stainless steel wire, and the stainless steel wire to the stainless steel base, respectively. As the stainless steel tube has the smallest cross-sectional area, the highest resistance in the whole circuit is at the stainless steel tube, about 0.5 Ohm, so the temperature is highest here too. I would recommend having some extra spare parts and testing the parameters of the spot welder in advance, as the stainless steel tube can easily break under unsuitable parameters. Finally the two Yb sources are filled into the corresponding stainless steel tubes.

Each oven is mounted in such a way that the outgoing atomic beam is directed towards the trapping area. The oven feedthrough replaces an XX inch window in the axial direction of the trap. the glass in the corresponding position of the 40K shield and 4K shield is also replaced with a round aluminium plate, the centre of which is a square hole with a 5mm side to pass through the Yb flux. As the cryostat has assembly errors, I would recommend preparing round aluminium plates with different opening positions in advance. Ultimately we need to be able to see the trap through the opposite window, with the square hole and the oven in the same line.

In the process of loading ions, when this stainless steel tube is heated resistively by an electric current, a spray of atomic Yb is produced. The temperature reached depends on the current and the time of operation. If either of these two factors is too high or too long, this can lead to rapid evaporation of the Yb and thus the formation of a spray dense enough to cover its surface (e.g. ion trap electrodes or vacuum windows). To prevent this, each oven is tested in advance. A stainless steel sheet is placed in front of the oven and then the oven is placed in a transparent vacuum chamber and the vacuum is reduced to approximately $4\text{E-}6$ mbar using a turbo-molecular pump, so that a test system can be set up. We tested each oven in turn, starting at 0 A and increasing the current by 0.1 A every 10 seconds, observing the change in vacuum level and the colour of the stainless steel sheet. We can observe both the darkening of the stainless steel sheet and the rapid rise in pressure, at which point the current value is the threshold current for the corresponding

oven. ^{171}Yb oven has a threshold current of 4.2A and ^{174}Yb oven has a threshold current of 3.9A, but the current values we use in practice will be lower than this threshold, the exact values need to be measured in the corresponding experiments. The exact values need to be measured in corresponding experiments, such as observing the fluorescence of Yb atoms and loading Yb ion.

3.6 Mechanics Frame

3.7 Optical and Imaging System

Whether trapping ions or manipulating them, we need lasers. In our laboratory, tunable diode lasers (Toptica) are used widely, mainly because these products are very well mature. For ion trap systems, a stable light source is very important. Experimentally, we need these lasers to be switched on and off quickly, typically in a few hundred nanoseconds. It is also necessary that these lasers can be stabilised over long periods of time and that these laser controllers have stable software systems. Laser stabilisation covers mode, frequency, power and polarisation. Typical laser stabilisation lasts from a few hours to a day, including laser frequency locking. This is sufficient for our trapped ion experiments, but longer stabilisation times are preferable. In the experiments, these stable lasers are used for: ion loading, Doppler cooling, optical pumping, state detection, repumping and sympathetic cooling. In addition to the laser light path into the cavity, I also built an imaging system to collect the fluorescence emitted by the ions, enabling real-time observation and state detection of the ions.

3.7.1 Laser Sources and Power Allocation

The light sources in the laboratory are placed on several separate optical tables. Since the principles of the optical path setup are similar, we can present the light sources and power allocation in a common way. The cryogenic trap platform requires a 370nm laser, a 399nm laser and two 935nm lasers. The two 935 nm lasers are shared with other ion trap platforms in the lab, one for trapping $^{171}\text{Yb}^+$ ions and the other for trapping $^{174}\text{Yb}^+$ ions. The 399nm laser is used for loading ions. Depending on the type of ion to be loaded, $^{171}\text{Yb}^+$ or $^{174}\text{Yb}^+$, we can change the wavelength of the 399nm laser. This 399nm laser is also shared with other trapped ion platforms in the lab and only one 399nm laser is needed. Since loading ions is not very frequent and most of the time we need to load $^{171}\text{Yb}^+$ ions, and modifying the wavelength of the 399nm laser will not affect the stable

trapping of the loaded ions.

The output power of a semiconductor laser is approximately XXmW, depending on the wavelength and model, the laser output power may vary a little. The output power of the 370nm laser (L1) is XXmW, the output power of the 399nm laser (L2) is XXmW, the output power of the 935nm laser (L3) is XXmW and the output power of the 935nm laser (L4) is XXmW.

As the nominal light output from the laser is linearly polarised, a power attenuation unit was formed using a half-wave plate (HWP) and polarization beam splitter (PBS) to split the laser output into two parts, which are separately coupled into the fibre. Each fibre will act as the light source for the next stage of the optical path, thus making the optical path a modular one. Each laser has one optical fibre connected to the wavemeter (C5, C6, C7, C8). Because polarisation stabilisation is not required, a single-mode fibre is used, with a typical power of approximately 50 μ W. The other fibres are the light sources for the rear optical paths (C1, C2, C3, C4) and require high power, typically 5 mW. At the same time their polarisation needs to be stable over time and we use single-mode polarization-maintaining fibres. In order to adjust the polarisation direction to match that of the single-mode polarisation-maintaining fibre, we use a polarisation adjustment unit consisting of a HWP and quarter-wave plate (QWP). We need to maximize the efficiency of the fiber coupling, which requires a good laser output mode and good mode matching, which can be done with a lens pair, I don't show this in the diagram.

The 370nm laser also has two splits: one (C9) is connected to the optical cavity for narrow linewidth frequency locking of the laser, and the other (C10) is set aside. 171Yb⁺ repumping beam requires XX sidebands, so the 935nm laser (L3) has a fibre EOM (E1) in the rear optical path.

3.7.2 Laser Frequency Stabilization

The target linewidth of the laser frequency locking determines the laser frequency locking scheme. In my experiments there is no need for ultra-narrow linewidth laser locking, so the laser locking scheme is relatively simple and I have mainly optimised the automatic control of the frequency locking process. The measurement and locking of the laser frequency can be achieved with a wavelength meter, which has a relatively low bandwidth of about 10 Hz because the sum of the measurement time of the multi-channel wavelength meter and the computer readout time is about 100 ms. The standard deviation of the output frequency of the laser locked with this scheme is about 1MHz,

which meets my needs with a 399nm laser and two 935nm lasers, or if only to trap a small amount of ions then also my requirements for a 370nm laser. The outgoing light from the laser is transmitted by optical fibres (C5, C6, C7, C8) to the input of the wavemeter, which is programmed to read the frequency on our PC and then programmed to adjust the voltage signal from the laser controller, thus creating a closed loop that locks the laser frequency. The wavemeter's measurements are affected by the environment, mainly air pressure and temperature. Therefore this frequency locking scheme will cause the locked laser frequency to be inaccurate due to inaccurate measurements, but this error is slow and periodic over time. So for 399nm laser and 935nm lasers we don't take this into account. I only calibrate the 370nm laser once in 1 hour or longer, by measuring the resonant frequency of the Yb⁺ ion and feeding it back to the wavemeter's lock point. It would be possible to automatically calibrate the wavemeter for measurement errors if the wavemeter had a locked reference light all the way through, such as a 780nm laser, but we have not done this because it is not necessary. The implementation of an automatic frequency lock is necessary as it will simplify the steps of daily operation. By laboratory standards these lasers need to be switched off when they are not in use, for example every night. I will adjust the operating parameters of the laser so that the laser mode can be stabilised back to a specific frequency range for approximately 10 minutes after each switch-on operation, which requires us to find a stable operating parameter for the laser. We then only need to program to communicate with the laser and the wavemeter to achieve automatic laser control and frequency locking.

The results of targeting the 370nm laser with a wavemeter are not good enough because the feedback speed is too slow. We can increase the feedback speed with the assistance of an optical cavity, which reduces the standard deviation of the output frequency of the 370 nm laser to 300 kHz. I built this optical path on a breadboard in which an optical cavity (U2; SA200-3B, Thorlabs) was placed. The outgoing light from the 370 nm laser (C9) is incident to the optical cavity. mode matching of the optical cavity is achieved by a pair of reflectors and lenses. Locking the 370nm laser to the optical cavity is achieved by feeding the output signal of the photodiode (D1) back to the voltage signal of the 370nm laser controller. In order to have the lock point at the point of maximum transmission light intensity of the optical cavity, I added a modulation signal to the current signal of the 370nm laser and demodulated the signal from the photodiode (D1). This solution uses a simple optical cavity to increase the bandwidth of the laser locking. This scheme

uses a simple optical cavity to increase the bandwidth of the laser locking. However, because environmental factors can cause the cavity length of the optical cavity to change, the locked frequency will change rapidly as the cavity length changes. I connected the voltage signal (S1) from the wavemeter output to the piezoelectric ceramic (P1) of the optical cavity, thus achieving a locking of the optical cavity length to the wavemeter.

3.7.3 Laser Modulation

Making the laser modulation a separate module allows for modularisation of the optical path, which facilitates maintenance and testing, and also reduces the size of the optical path into the cavity, which in turn reduces the area of the breadboard where the cryogenic trap vacuum chamber is located. The main source of laser leakage during laser modulation is the higher order modes of the laser and stray light from the crystal during modulation. Adding a stage of fibre coupling can act as a spatial filter and help reduce leakage.

Experimentally, I need to add sidebands to the 370nm laser, the 14.7GHz sideband (E2) for Doppler cooling and the 2.105GHz sideband (E3) for optical pumping. the electro-optic modulator (EOM) can implement these features. The frequency and modulation depth of the sidebands can be controlled by controlling the frequency and amplitude of the EOM input microwave signal. In addition, I need to control the frequency shift and power of the 370nm laser. This is because the difference in frequency required for Doppler cooling and state detection is approximately 12MHz, and the frequency variation measured during calibration of the system can be compensated for by adjusting the frequency shift of the 370nm laser. The acousto-optic modulator (AOM) provides these features. By controlling the frequency and amplitude of the microwave signal input to the AOM (A1) the frequency of the laser shift and the laser power can be controlled.

The light source from the 370nm laser is fed to the laser modulation module via a single-mode polarization-maintaining fibre (C1), which is reflected by a beam sampling mirror and enters the laser monitoring module (U3). A number of signal acquisition modules are integrated into the laser monitoring module to help me monitor the quality of the light source over time, including measurements of power, polarisation, laser mode and others. The main light source is modulated by two cascaded EOMs, the modulation depth of which can be maximised by adjusting the HWP. Part of the laser is coupled into the fibre (C12), which is then used for sympathetic cooling. To achieve the frequency shift, I built a double-pass configuration based on a 4f optical system, where the PBS serves to separate the incident light from the returned light by 90°, adjusting the HWP at the front

to maximise the efficiency of the incident light and the HWP at the back to maximise the efficiency of the diffraction from the AOM. When the laser passes through the AOM, 0 order light is discarded and +1 order light is returned to the AOM by a 4f optical system consisting of a lens and a D-shaped pickoff mirror. The +1 order beam from the reflected beam passes through the QWP twice and is then reflected by the PBS into the fibre (C11), this light is then used for global cooling, pumping and detection. There is a mechanical shutter (N1) in front of the fibre, which serves to completely shut off the light and reduce leakage.

3.7.4 Optical Layout of Cryostat Breadboard

Due to the large base area of the cryostat, the area left for the optical path on the breadboard is relatively small. the main function of the optical path built on the breadboard of the cryostat is to shape the beam into a specific shape and then inject it into the cavity. There are four windows on the Cryostat that are used to inject the laser. The laser light exiting the fibre collimator (C2, C3, C4, C11, C12) is first polarised by the QWP and HWP and then expanded by the lens pairs (T1, T2, T3, T4) to a suitable spot size, typically with a Gaussian diameter of approximately 10 mm.

3.8 Electronic Devices

CHAPTER 4 EXPERIMENTAL PROCEDURE

4.1 Start CryoServer

4.2 Cooling-down and warm-up

The cryogenic trapped-ion system is a relatively complex experimental system, and we need the system to be stable over a long period of time so that the reproducibility of the measurement results is high. Although the cryostat's core component, the cold head, can run continuously for more than XX hours, the maximum time this cryostat can run continuously is limited by the stability of the power supply, the stability of the laboratory temperature and humidity, and whether the exchange gas chamber is leaking. It took us about three years to get the system into a stable long-term state, after which we conducted a series of physical experiments on the experimental platform. However, during the three-year commissioning process, we inevitably need to conduct the cycle of cooling-down, malfunction, warm-up, and upgrade, during which the standardized operation helps to make the physical parameters of the system more repeatable, so we have developed a standardized operation procedure for this system.

4.2.1 Maintenance of the exchange gas chamber

If the cold head does not need to be removed for servicing, the exchange gas chamber does not require frequent maintenance and is always in an independent and stable state, whether it is being cooled down or warmed up.

The exchange gas chamber uses helium gas with a purity of XX. When we expose the exchange gas chamber to atmosphere or when it is first used, the internal gas needs to be purified. According to the cryostat manufacturer's recommendations, a purification is also required after several months of continuous running, but this is not normally done when the system is stable for a long period of time. How often the exchange gas chamber needs to be purified depends on the rate of impurity gases (nitrogen, oxygen, water vapour etc.) leaking in from the atmosphere.

When we need to purify the helium gas in the exchange gas chamber, the exchange gas chamber is first evacuated continuously for 0.5 hours with a dry scroll pump (Agilent IDP-7), then the valve connected to the dry scroll pump is closed and the valve connected to the helium gas is opened. The auto gas charging system will then raise the pressure to

1.03 bar and finally we close the valve to the helium gas. In general, the above operation is repeated three times to purify the helium gas in the exchange gas chamber.

When we need to cool down or warm up the system, and also when the system is running at low temperatures for a long time, we simply open the valve to the helium gas and keep the auto gas charging system running steadily.

4.2.2 Cooling-down

In the Cooling-down procedure, the physical parameters of the vacuum chamber are mainly adjusted and observed. The vacuum chamber is first connected to a turbo-molecular pump (TPS-compact Turbo Pumping System) via the angle valve and after approximately 48 hours of continuous operation the vacuum chamber reaches a vacuum level close to UHV. The ion gauge is switched on and reaches an indication of $5\text{E-}8$ mBar, at which point we do not need to degas the ion gauge as the room temperature zone of the vacuum chamber does not eventually fall below $1\text{E-}10$ mbar. Now we need to perform a time limited activation of the NEG Pump for 1 hour, then we perform several degas of the Ion Pump and keep the Ion Pump on. Now that the activation of the NEG-Ion Pump is complete, we close the angle valve and wait about 1 hour for the ion gauge to gradually decrease to $3\text{E-}9$ mbar, when the vacuum chamber reaches the UHV vacuum level. We turn on the cold head and the temperature stabilize system, which will finish cooling down within 5 hours, but the system will not reach final stabilization for more than 24 hours. The temperature of the 4K stage is finally stabilised at 6K and the ion gauge is stabilised at $3\text{E-}10$ mbar.

4.2.3 Warm-up

The warm-up procedure is much easier than the cooling-down procedure because we do not need to obtain UHV during this process. we turn off the cryogenic and vacuum related instruments: the NEG-Ion pump, the ion gauge, the cold head. We can use the heater in the temperature stabilize system to heat the cryostat to speed up the warming process to room temperature, which takes about 24 hours or more. The system can also be allowed to warm up naturally to room temperature, which takes about 48 hours or more. Next, if necessary, we can move the cryostat into the service area for servicing. Before moving it out, we need to record the readings of all optical and electrical instruments. As the imaging system is embedded in the re-entrant window, we usually need to remove the objective lens.

REFERENCES

APPENDIX A 补充内容

附录是与论文内容密切相关、但编入正文又影响整篇论文编排的条理和逻辑性的资料，例如某些重要的数据表格、计算程序、统计表等，是论文主体的补充内容，可根据需要设置。

A.1 图表示例

A.1.1 图

附录中的图片示例（图 A.1）。

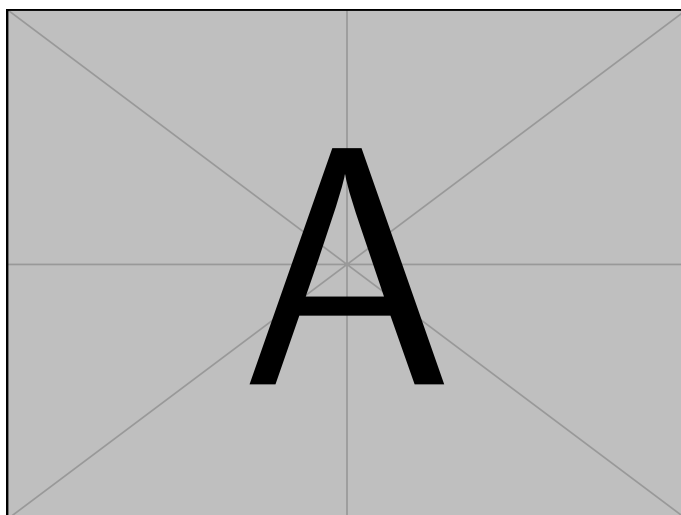


Figure A.1 附录中的图片示例

A.1.2 表格

附录中的表格示例（表 A.1）。

Table A.1 附录中的表格示例

文件名	描述
thuthesis.dtx	模板的源文件，包括文档和注释
thuthesis.cls	模板文件
thuthesis-*.bst	BibTeX 参考文献表样式文件
thuthesis-*.bbx	BibLaTeX 参考文献表样式文件
thuthesis-*.cbx	BibLaTeX 引用样式文件

A.2 数学公式

附录中的数学公式示例（公式 (A.1)）。

$$\frac{1}{2\pi i} \int_{\gamma} f = \sum_{k=1}^m n(\gamma; a_k) \mathcal{R}(f; a_k) \quad (\text{A.1})$$

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声 明

本人郑重声明：所呈交的学位论文，是本人在导师指导下，独立进行研究工作所取得的成果。尽我所知，除文中已经注明引用的内容外，本学位论文的研究成果不包含任何他人享有著作权的内容。对本论文所涉及的研究工作做出贡献的其他个人和集体，均已在文中以明确方式标明。

签 名：_____ 日 期：_____

RESUME

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197×年××月××日出生于四川××县。

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在学期间完成的相关学术成果

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COMMENTS FROM THESIS SUPERVISOR

论文提出了.....

RESOLUTION OF THESIS DEFENSE COMMITTEE

论文提出了.....

论文取得的主要创新性成果包括：

1.
2.
3.

论文工作表明作者在 ××××× 具有 ××××× 知识，具有 ×××× 能力，论文 ××××，
答辩 ××××。

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×××（门类）学博士/硕士学位。